A microscopic view of a sensor array, showing a grid of small, square elements. The array is illuminated from above, creating a grid of light and shadow. The background is a soft, out-of-focus blue and white, suggesting a clean, technical environment.

Laser Based Magnetic Field Sensor Formation for GMR / TMR Sensor Arrays

Content

1. About 3D-Micromac
2. Motivation
3. Our Solution
4. Production Example



3D-Micromac – Micromachining Excellence

We are the leading specialist in laser micromachining.

Our mission:

- **Development and production** of unique process and machine solutions for various high-tech markets
- Customer support from **product development to high-volume production**
- **Enabling** laser micromachining techniques for **new devices**
- Superior production **efficiency** and reliable **process stability**



“Our international customers place great value on future-oriented and user-friendly processes. Our solutions help them increase production efficiency and lower cost”.

Uwe Wagner, CEO

3D-Micromac – The Specialist in Laser Micromachining

Key Facts



- » Founded in **2002**
- » 180 employees
- » Based in **Chemnitz, Germany**
- » Branch offices in **US** and **Taiwan**

Services



- » **Feasibility studies & process development** in-house
- » Production of limited lots and ramp-up production
- » **Worldwide** sales & service network

Machine Base



- > **600 installations worldwide**
- > **50 systems in semi industry**
- > **150 systems in glass/display**
- > **30 systems in microdiagnostics**
- > **110 systems in photovoltaics**
- > **30 systems in roll-to-roll production**

Target Markets & Products



» Semiconductor



» Glass & Display



» Microdiagnostic



» Photovoltaic

Motivation for Laser xMR



Growing Demand for Magnet Sensor Devices

... driven by ...

1. Sensors for IoT

- Integrated rotation sensors
- e-compass

2. Appliance

- Brushless DC motor angle sensor
- Position sensors

3. Automotive

- Power steering angle control
- Electronic throttle control
- Brushless DC motor angle sensor

4. Mobile devices

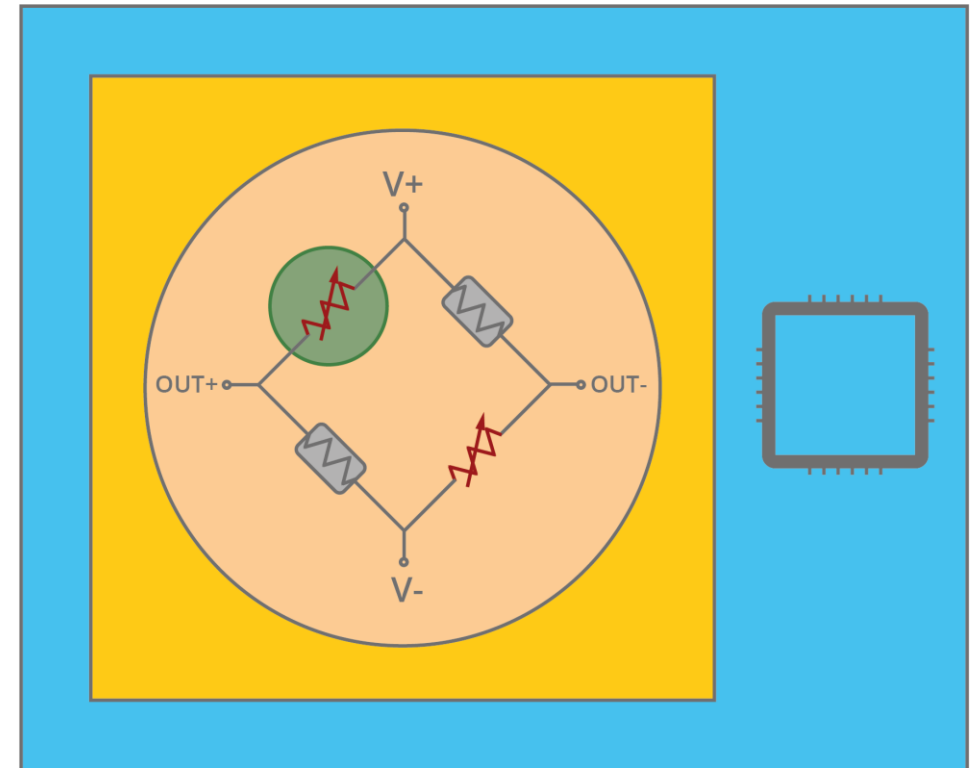
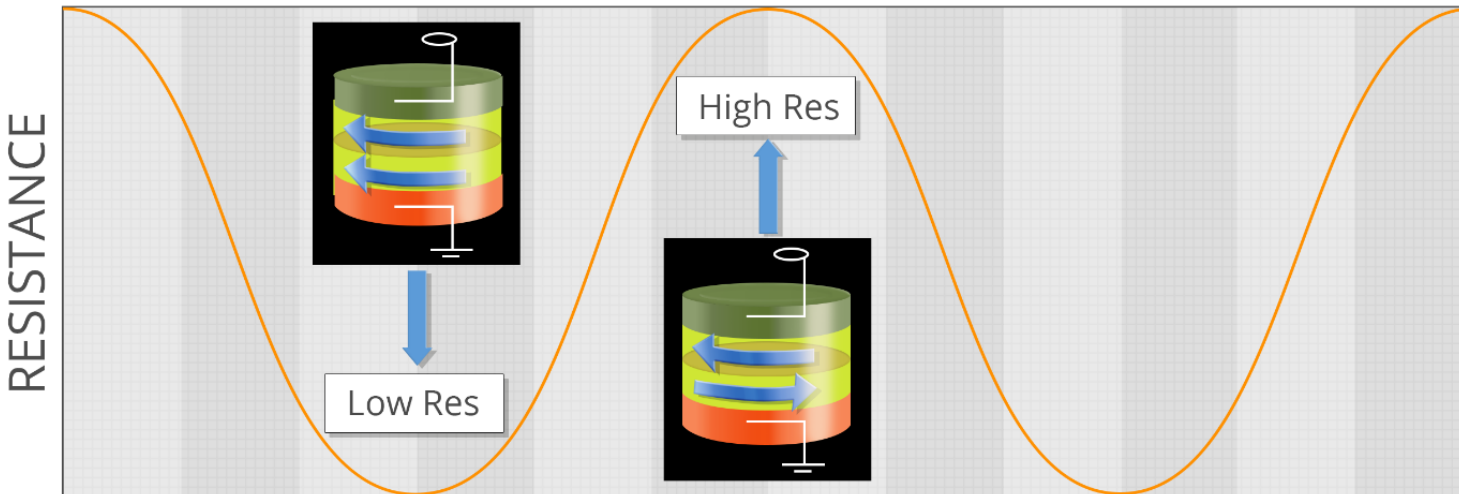
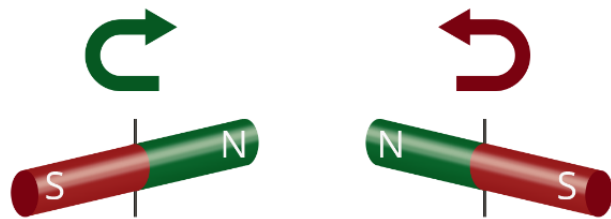
- e-compass



Magnetic Orientation Sensor Systems

Aim: Build very sensitive magnetic orientation sensor chips

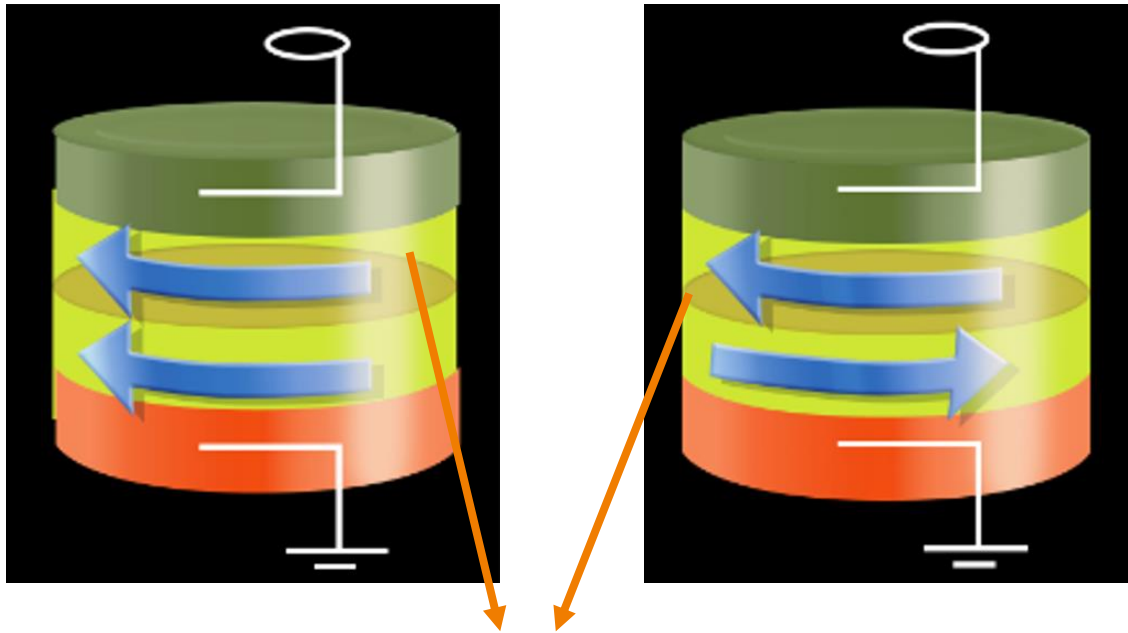
- Using GMR or TMR (Giant or Tunneling Magneto-Resistance) sensors
- Using a Wheatstone bridge circuit



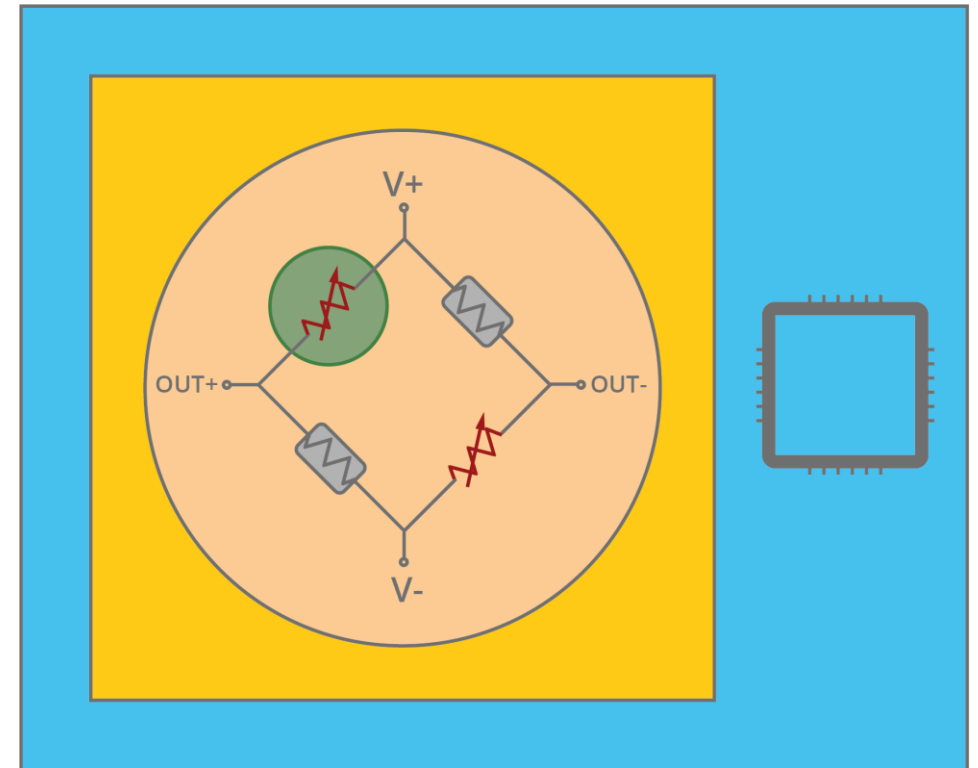
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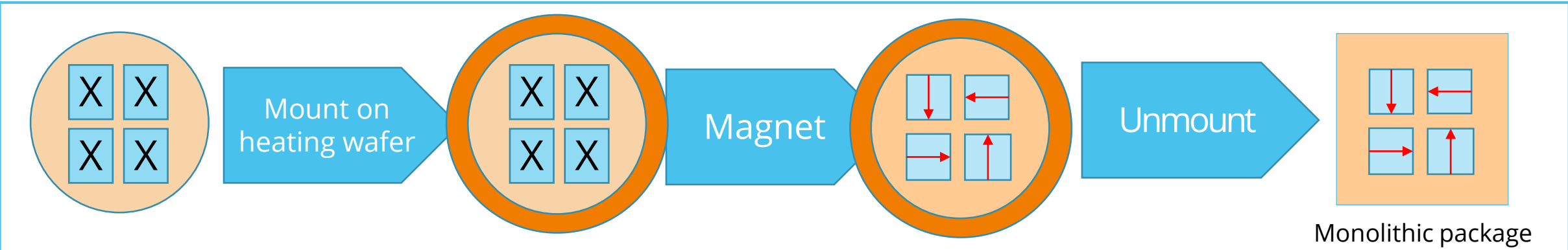
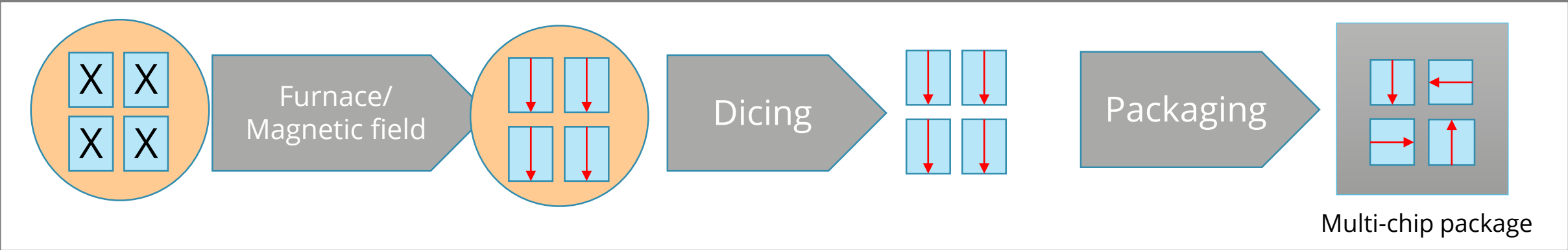
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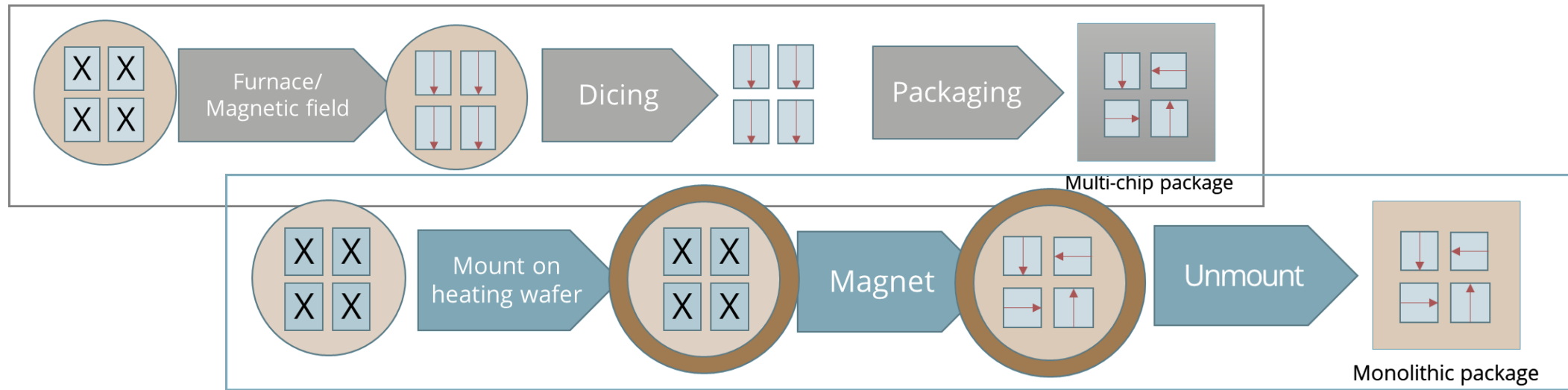
One layer needs to be pinned → magnetic field + heat



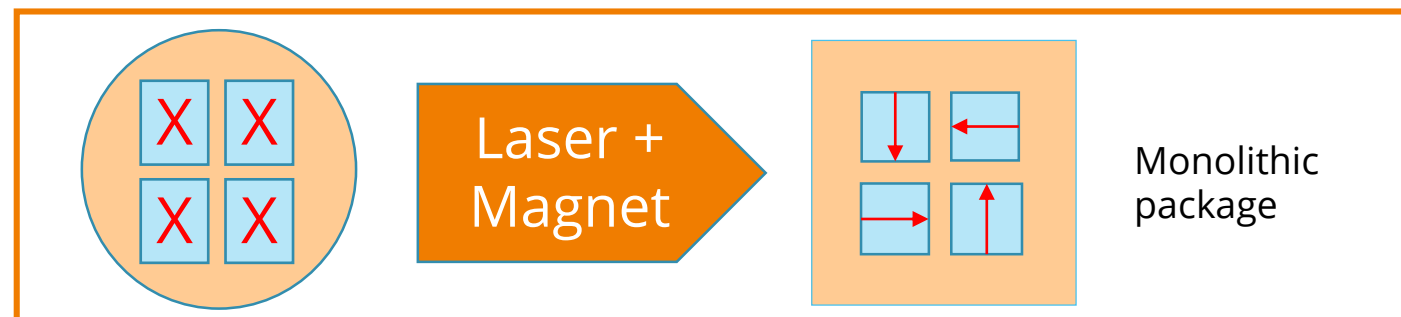
Sophisticated Production Today



Sophisticated Production Today



NEW: Our solution



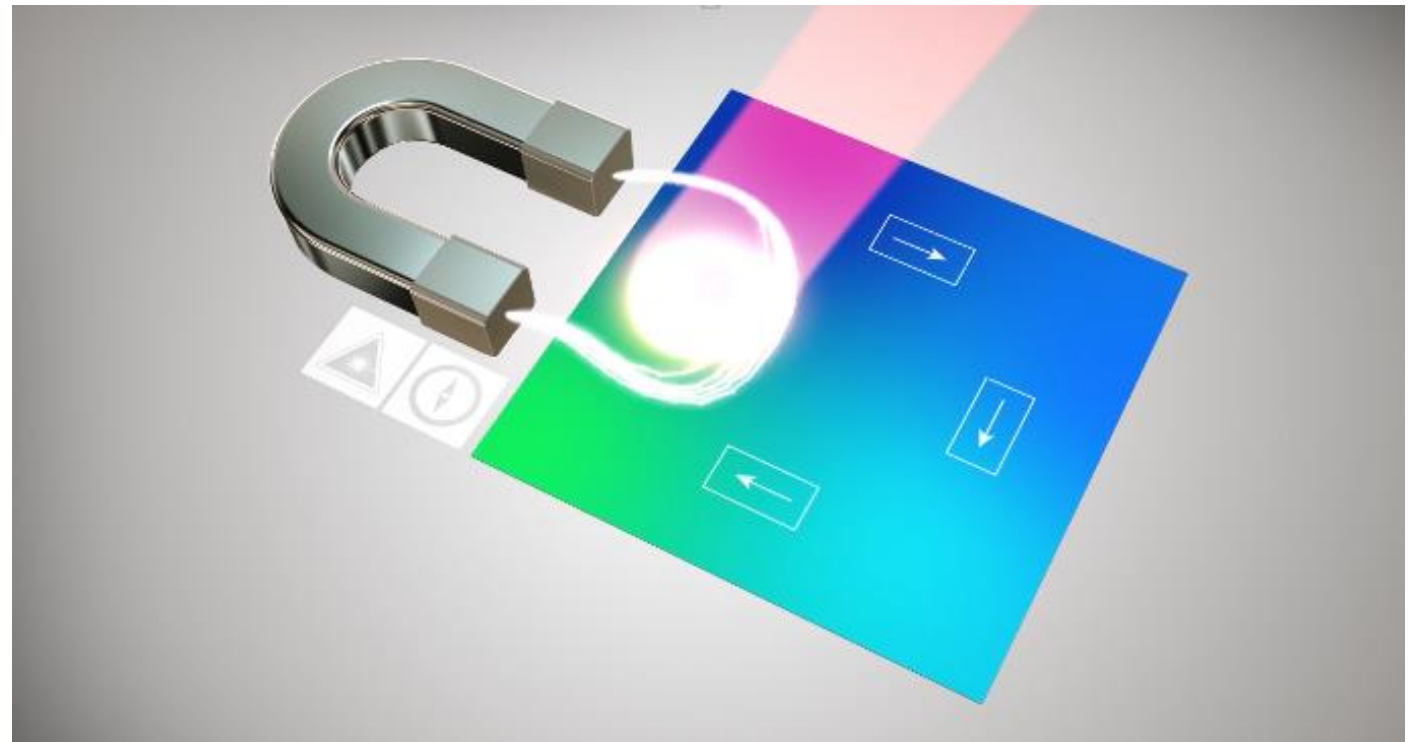
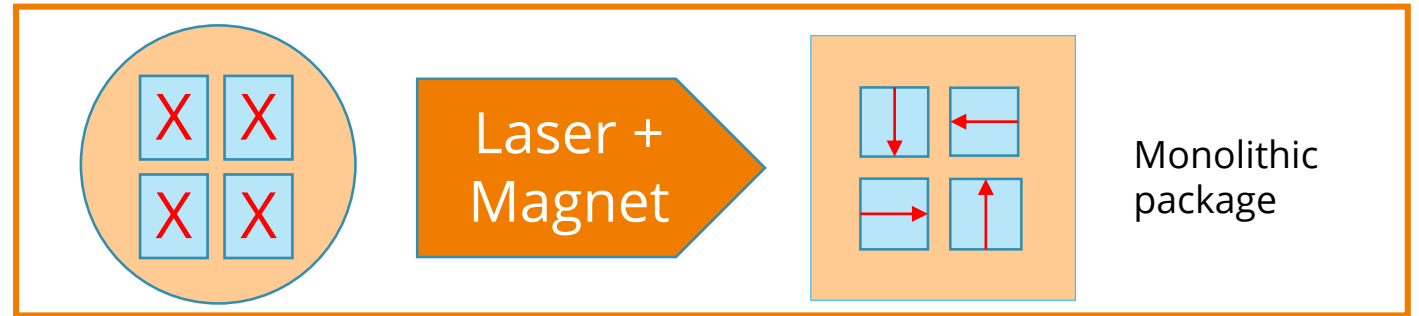
Principle of Laser Pinning

Process description:

- Strong magnet is positioned over the sensor field
- Laser shoots “through” the magnet and heats up the sensor field
- Laser pulse only at sensor field area, using an adjustable laser field dimension → no heating of nearby electronics
- On the fly processing → high throughput possible

Laser parameter:

- Wavelength: 1064 nm
- Pulse length: adjustable in ns range



microVEGA™ xMR



Setting new standards for
magnet sensor production

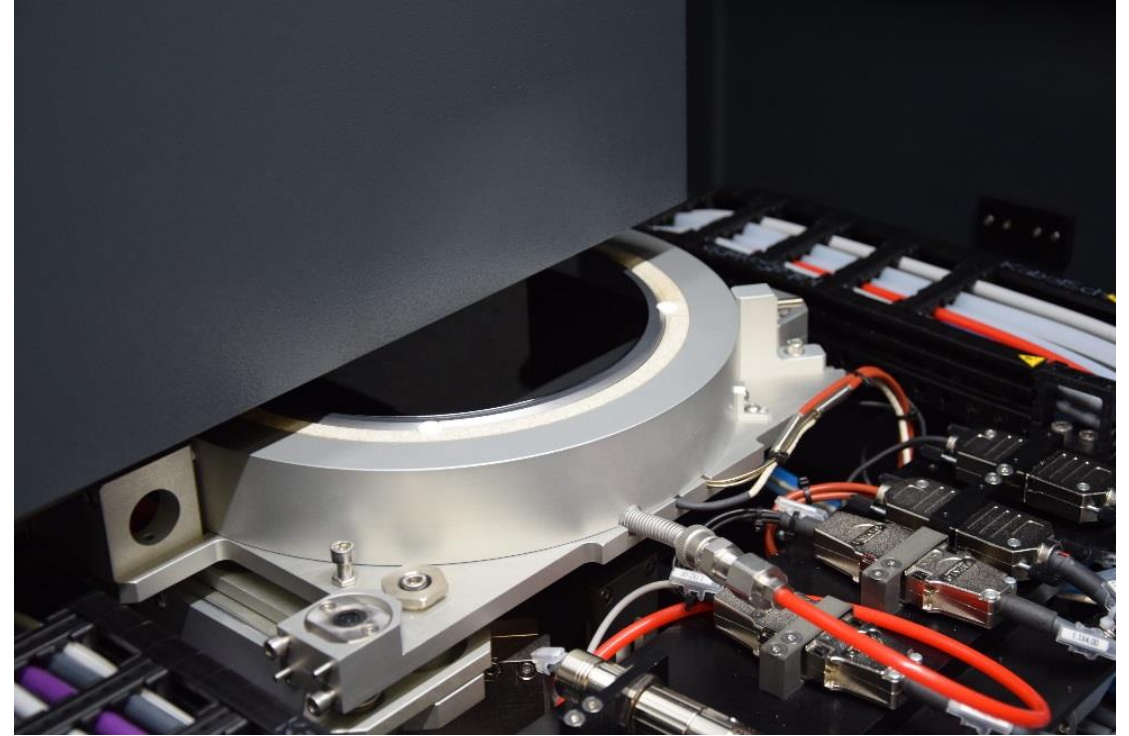
microVEGA™ xMR at a Glance

- High performance laser annealing system
- Standard working area for 300 mm wafer
- Novel solid state laser based process
- Integrated process control
- Automatic wafer handling

Throughput estimation* (very product specific):

- 520,000 sensors per hour (a customer sample)

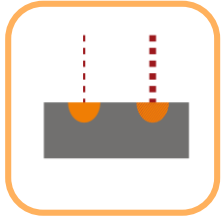
*depending on sensor and wafer design



Inside microVEGA™ xMR

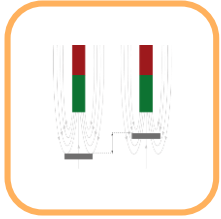
Wafer - Parameter - Fitting

The following parameters can be changed by recipe:



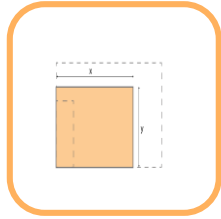
Laser pulse energy

Variation of laser power



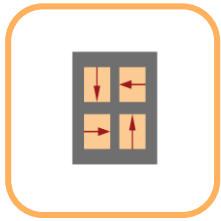
Magnetic flux

Up to **0.65 Tesla**
Variable by height of the magnet



Sensor dimensions

Rectangular shapes changeable by recipe:
10 μm x 10 μm to 300 μm x 300 μm

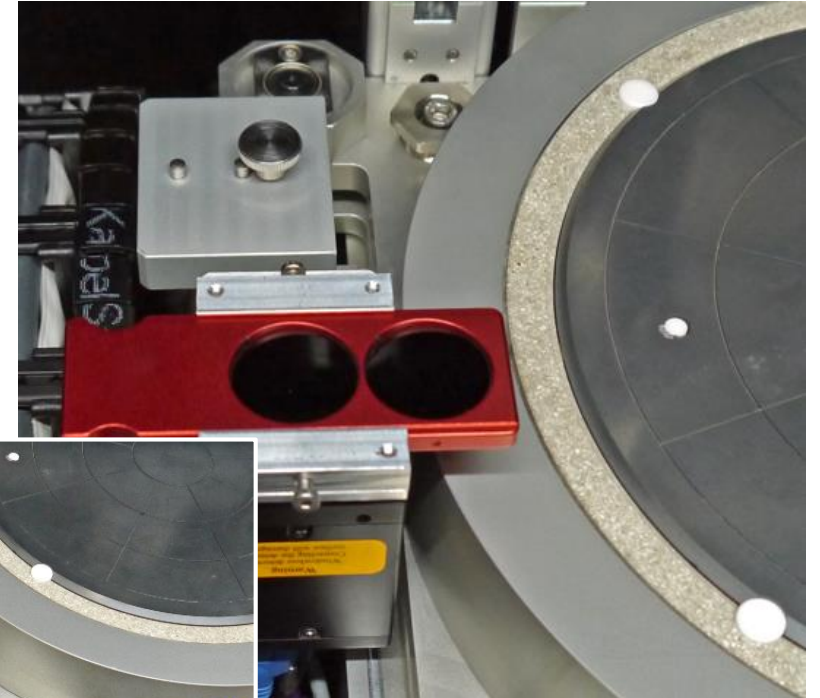


Orientation

Rotatable by **360°**
Accuracy: $\pm 0.01^\circ$

Magnet Sensor Processing - Sensor and Process Control

- Energy sensor at laser exit
- Power sensor at chuck level
- Beam analyzer at wafer level or laser exit
(free positioning, high resolution cam 1,600 x 1,200 pixel)
- Gauss-meter integrated
- All relevant data are saved in log files



Beam profiler in working plane
(beam profile measurement)

Gauss meter probe

Production Example: Crocus Technology

microVEGA™ xMR installed at Crocus Technology

- Used for programming monolithic TMR magnetic sensors
- Following quality assessment results are shown

Detailed quality assessment results
available on request!

Contact us on:

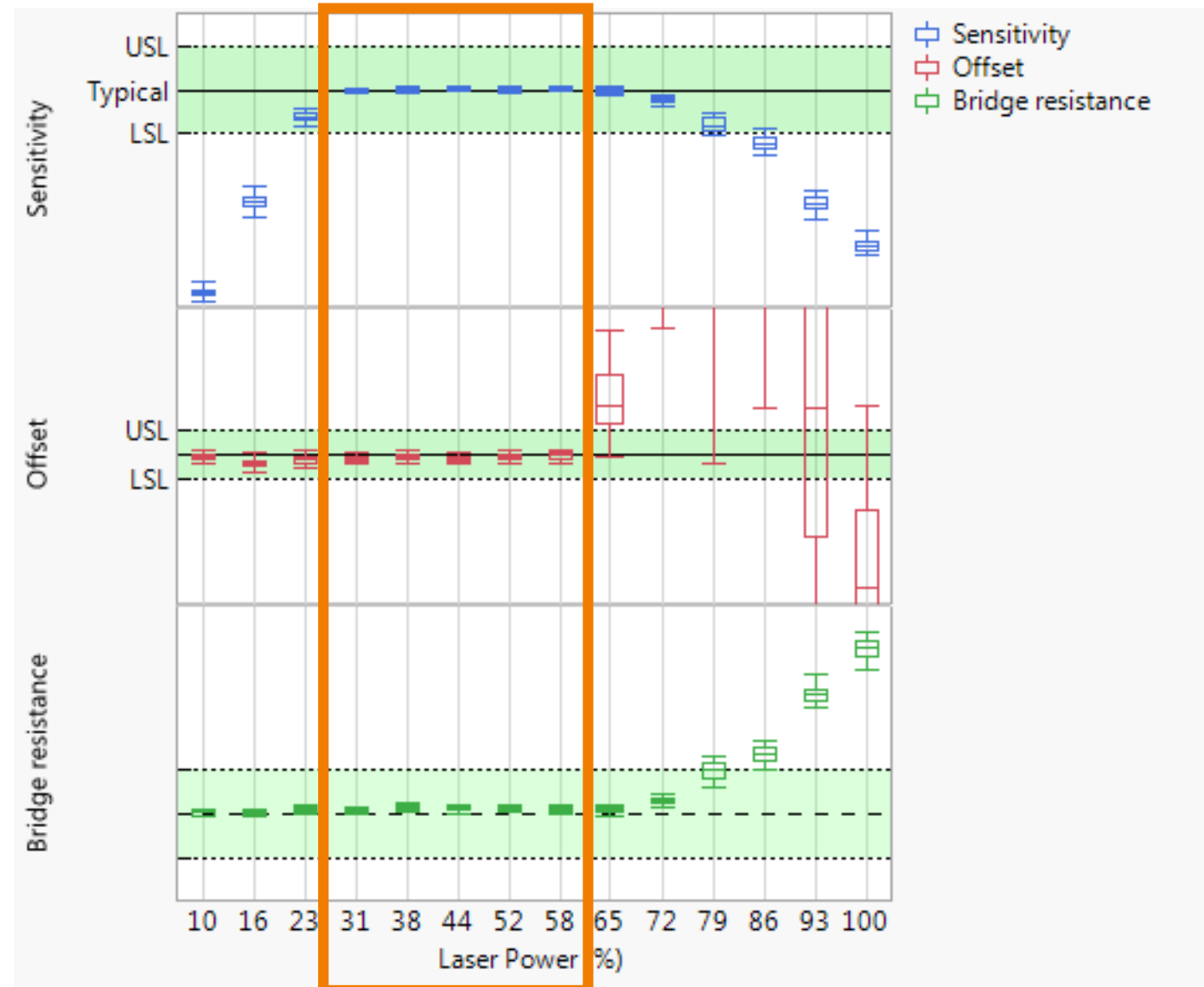
www.lasersensorformation.com



Variation of Laser Power

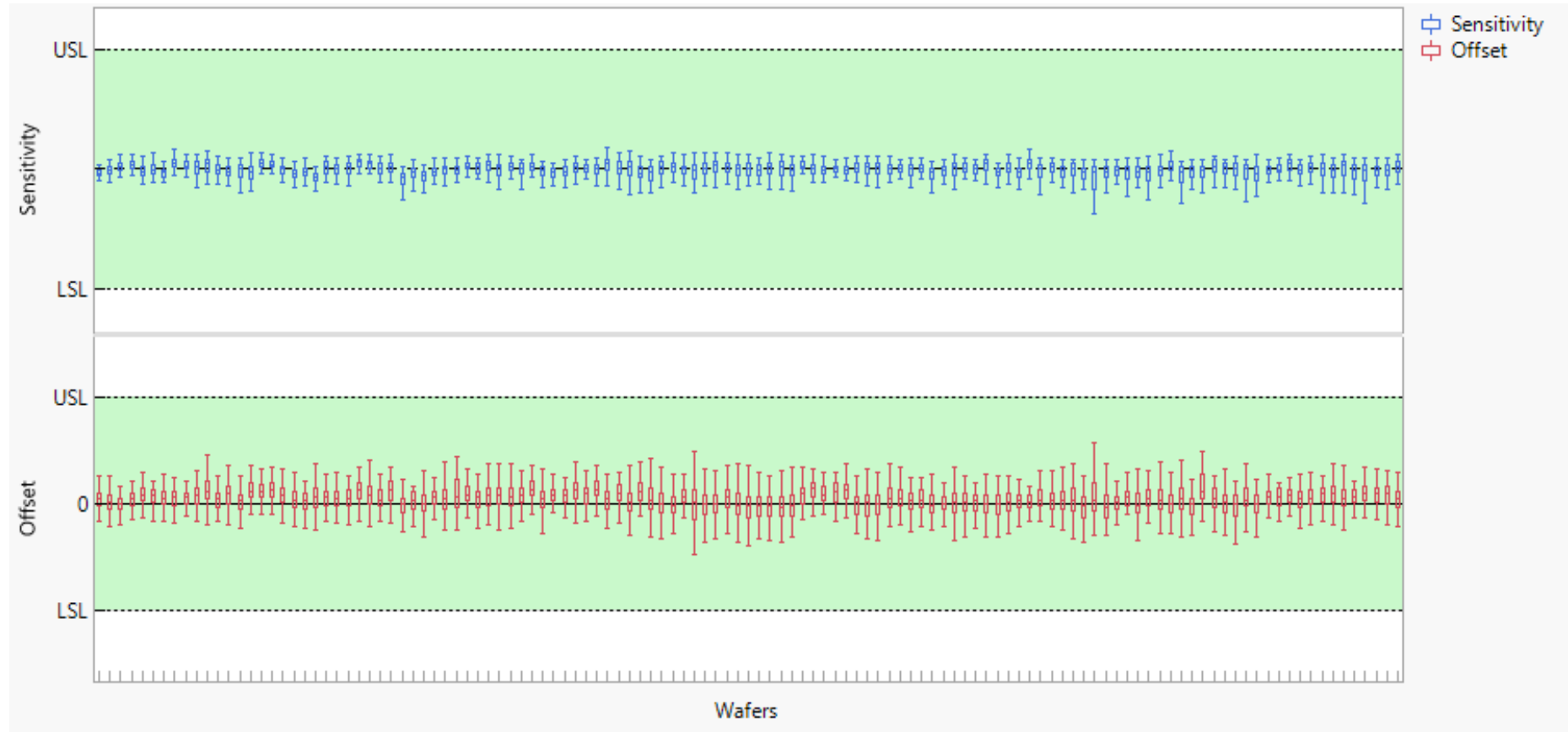
- Variation of the laser power of each single laser pulse
- Each 100 devices across one wafer
- Analysis of
 - Sensitivity → maximum sensitivity is the quality criteria
 - Offset → mismatches between sensor branches
 - Bridge resistance → overall indicator of sensor structural integrity

- ✓ High pinning quality
- ✓ High reproducibility from device to device
- ✓ Large laser power range



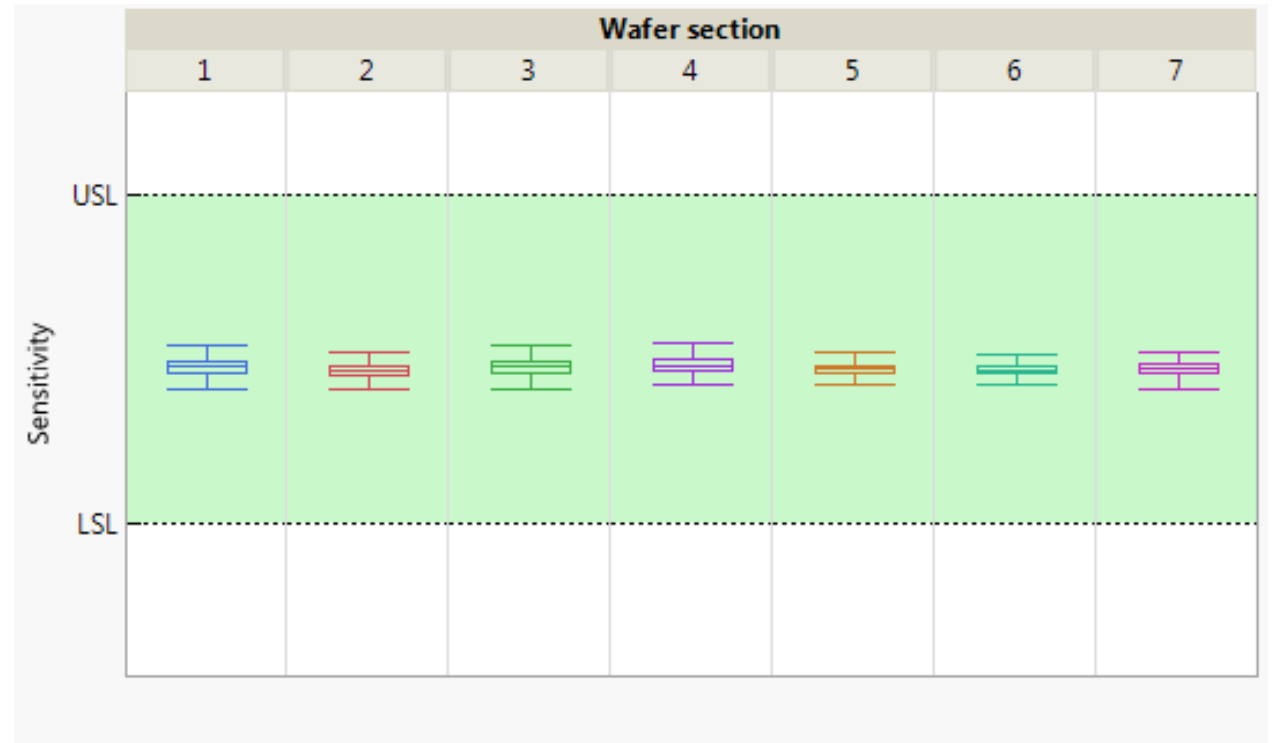
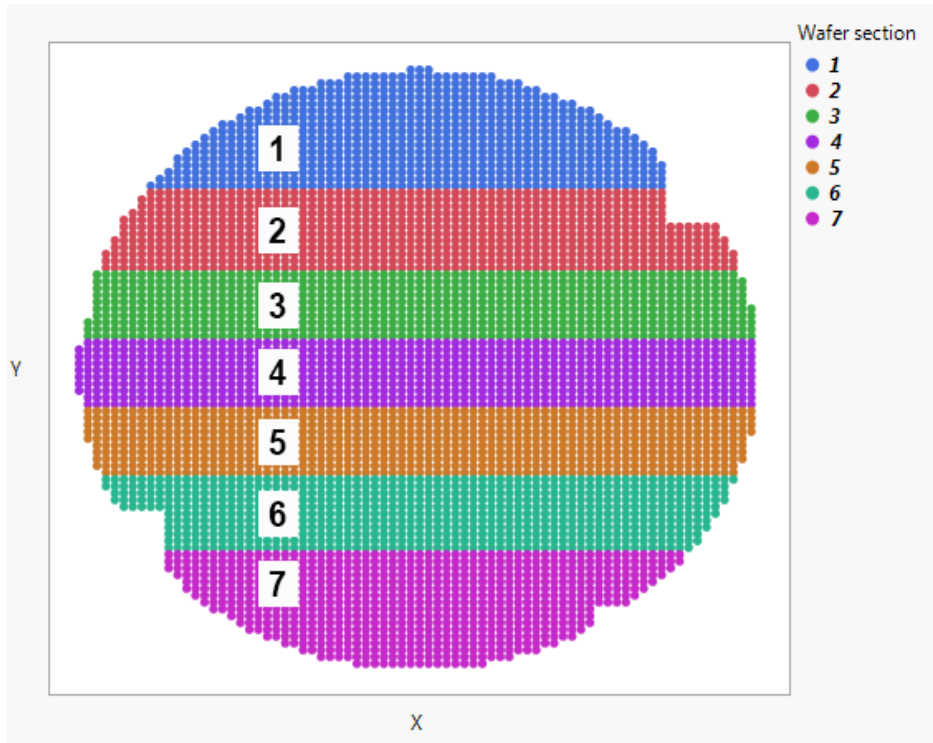
Wafer-to-wafer Reproducibility

- Sensitivity and offset across wafer
- Sample size: 120 wafers



- ✓ Sensitivity uniformity below 2%
- ✓ Demonstrated for 120 wafers

Homogeneity over one Wafer



- Sensitivity evaluation over one wafer
- Evaluation of equal number of sensors in 7 lines
- Laser processing horizontal line by line

- ✓ highly reproducible median sensitivity
- ✓ narrow and reproducible sensitivity distributions

microVEGA™ xMR – Summary

- **Cost-efficient production** of monolithically integrated sensor chips in just one production step
- Very high energy homogeneity - resulting in **improved sensor quality**
- Enables the **production of smaller sensors**
- Unique selectivity and maximum precision for **more devices per wafer** or **new sensor designs**
- High temperature gradient allows sensor location directly **next to read-out electronics**
- **Easily adjustment** of the magnetic orientation, sensor position and sensor dimension
- **New sensor designs** on monolithic packages possible
- High precision and high repeatability is **proven in production**



microVEGA™ xMR

3D-Micromac – What We Offer For Sensor Field Formation

- **Machine Solutions** - Our laser systems deliver leading edge processes with superior production efficiency.
- **Process development** - We fully support our customers in the qualification of product ideas as well as in the development of stable laser processes for production facilities.
- **Contract manufacturing** - With our unique process expertise we manufacture high-quality components as contract manufacturing service for you.
- **After-Sales Service** - Our qualified service team is available around the clock and worldwide, offering fast and reliable service.



Thank you for your attention!

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